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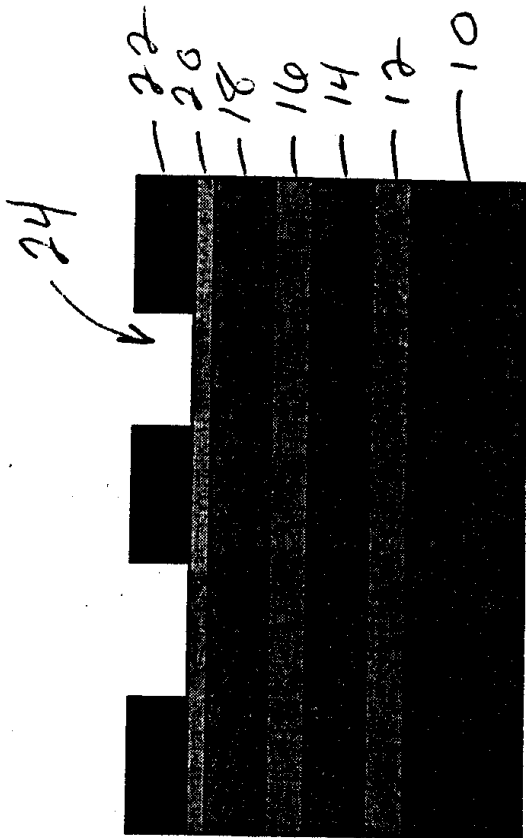


Figure 1

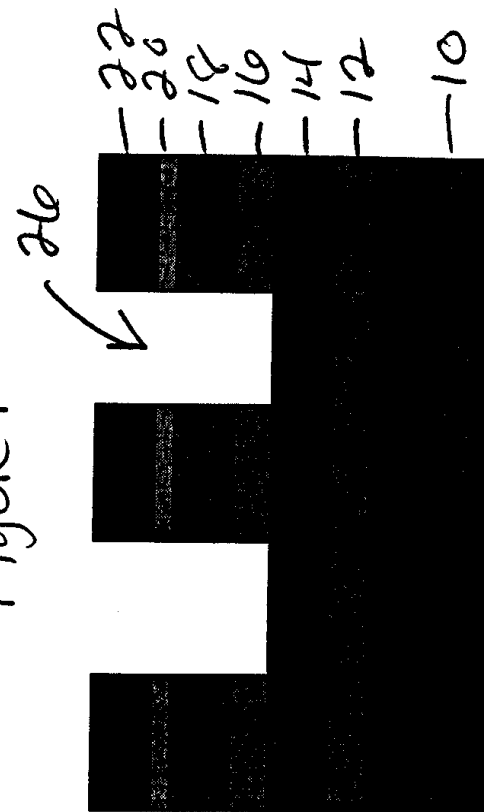


Figure 2

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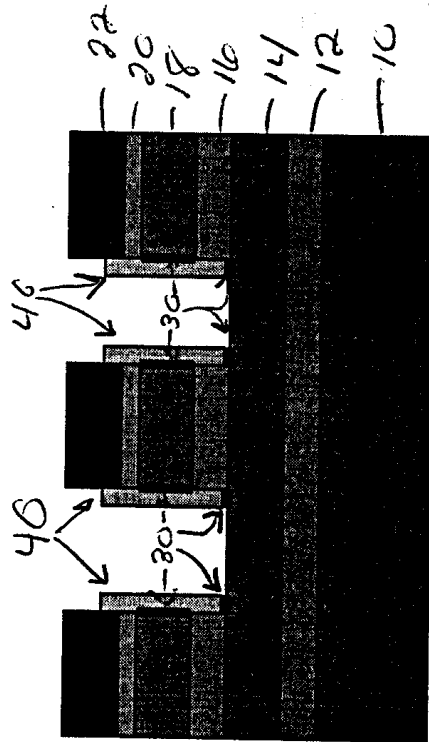


Figure 4

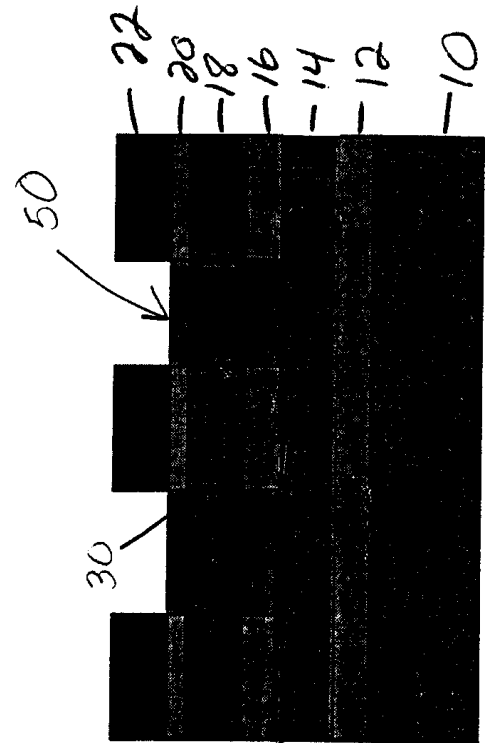


Figure 5

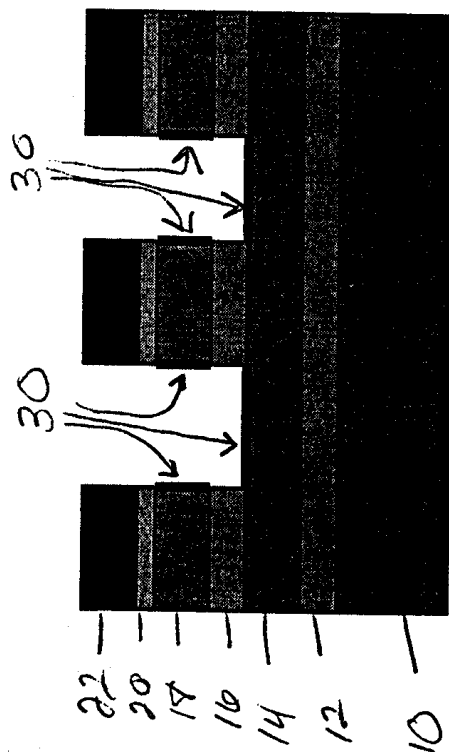


Figure 3

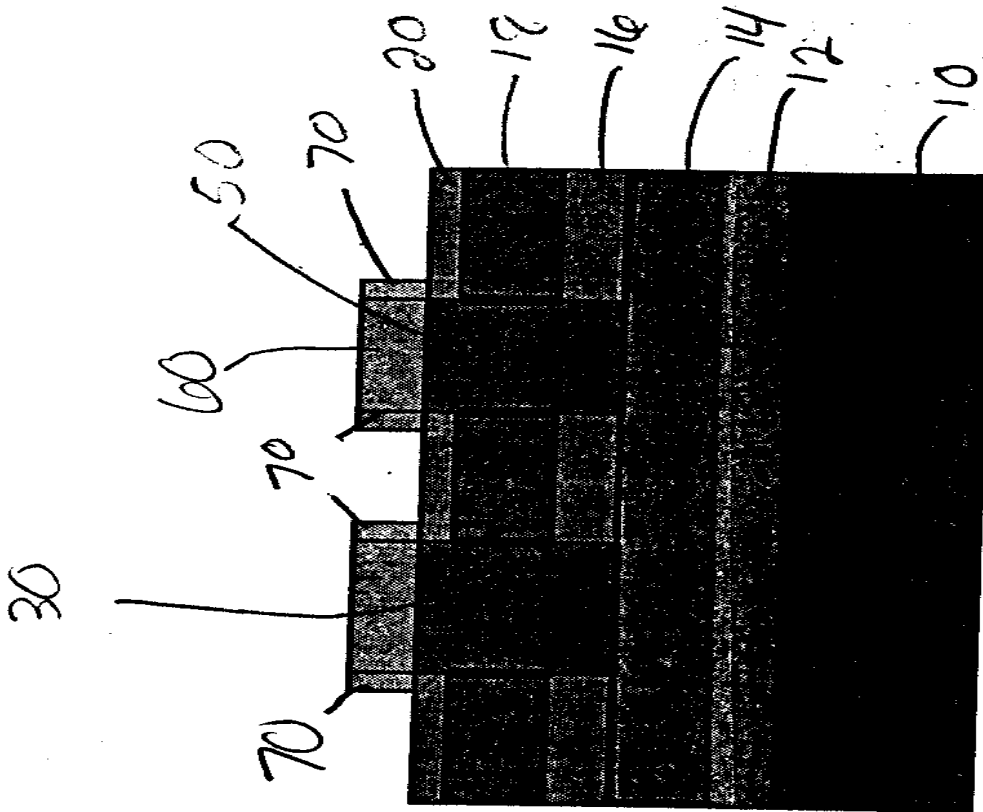


Figure 7

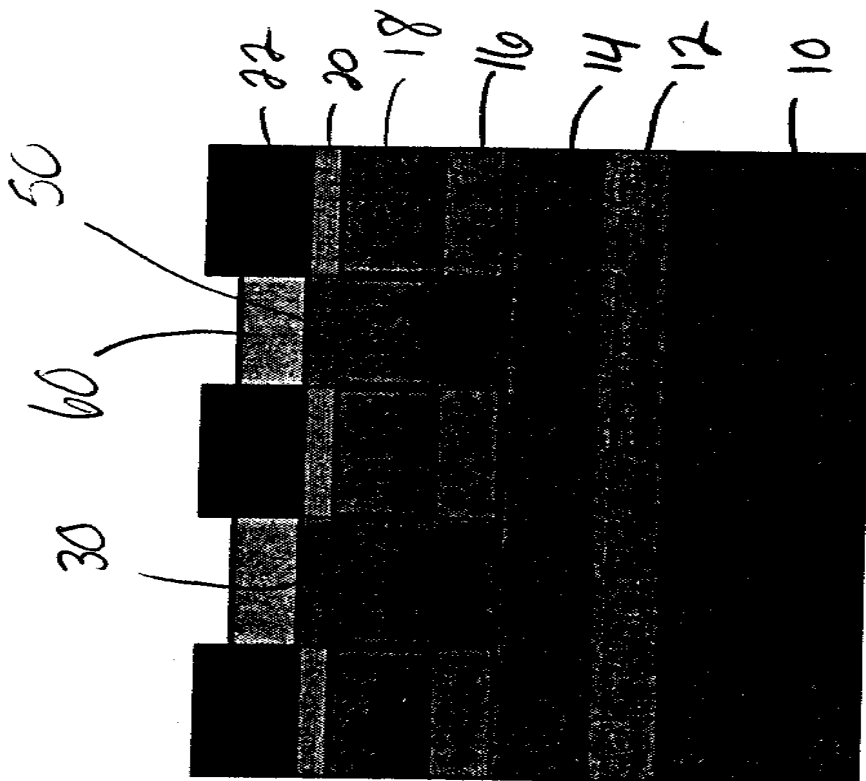


Figure 6

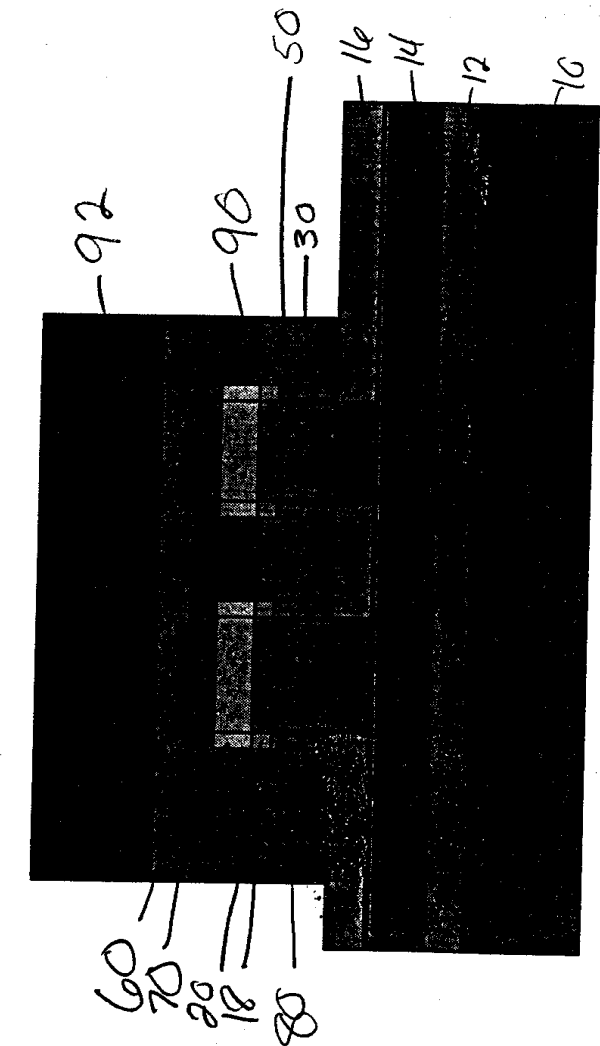


Figure 8

Figure 9

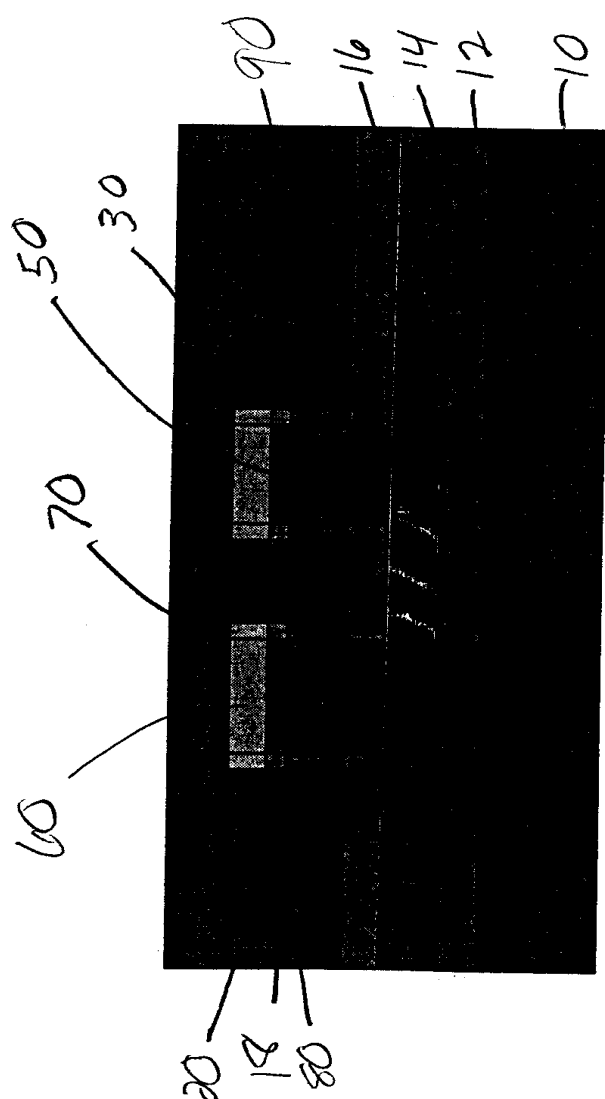


Figure 10

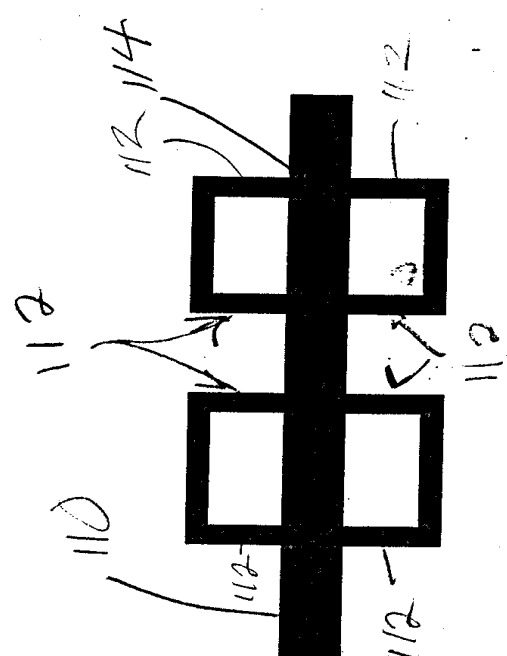


Figure 11

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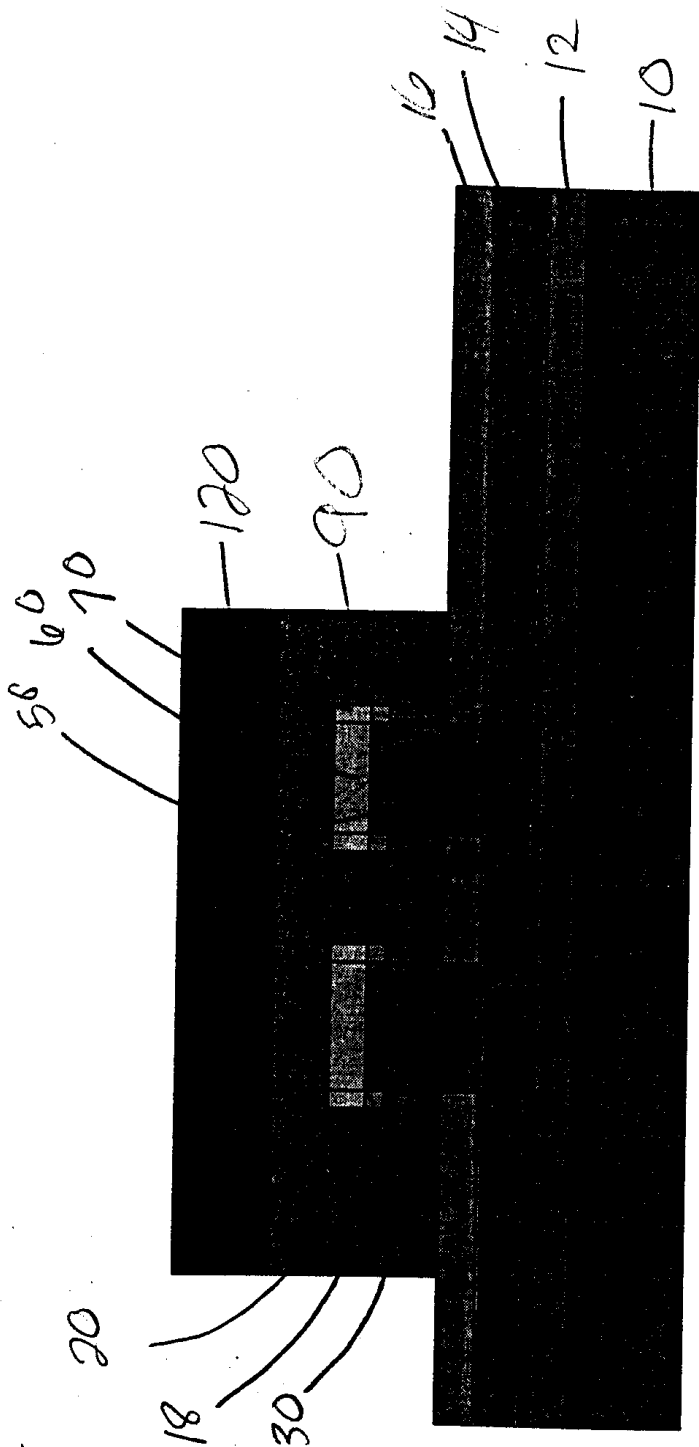


Figure 12 50 60 70 90

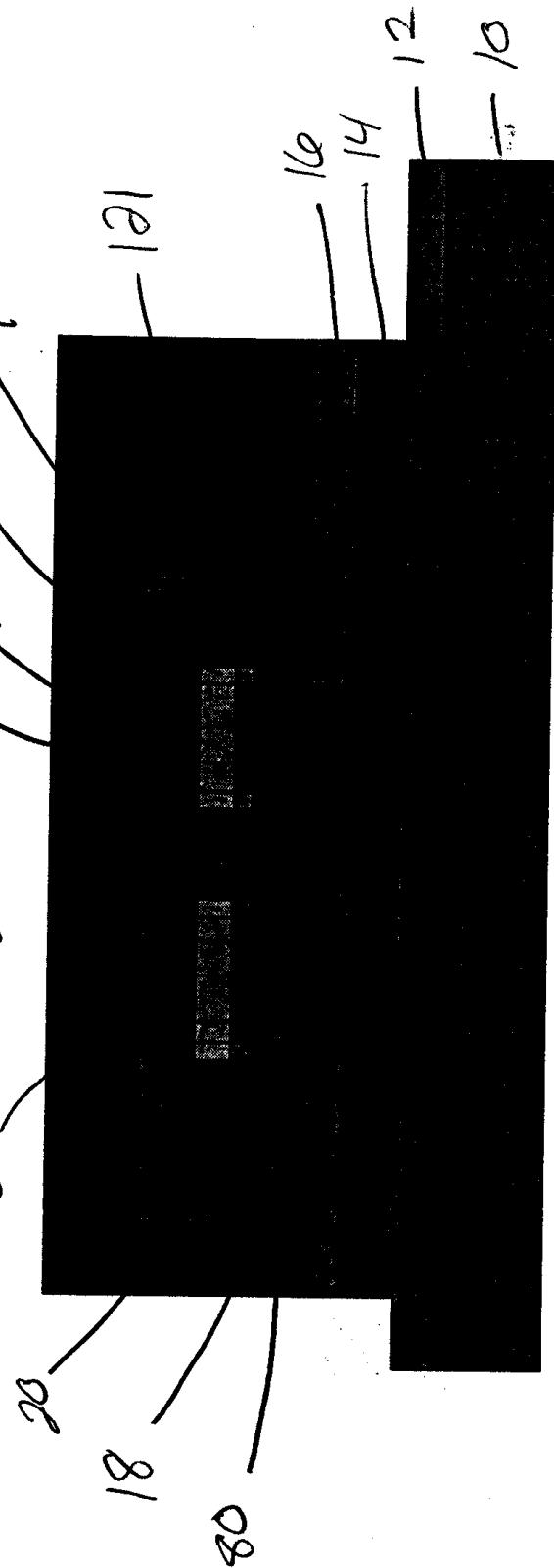


Figure 13

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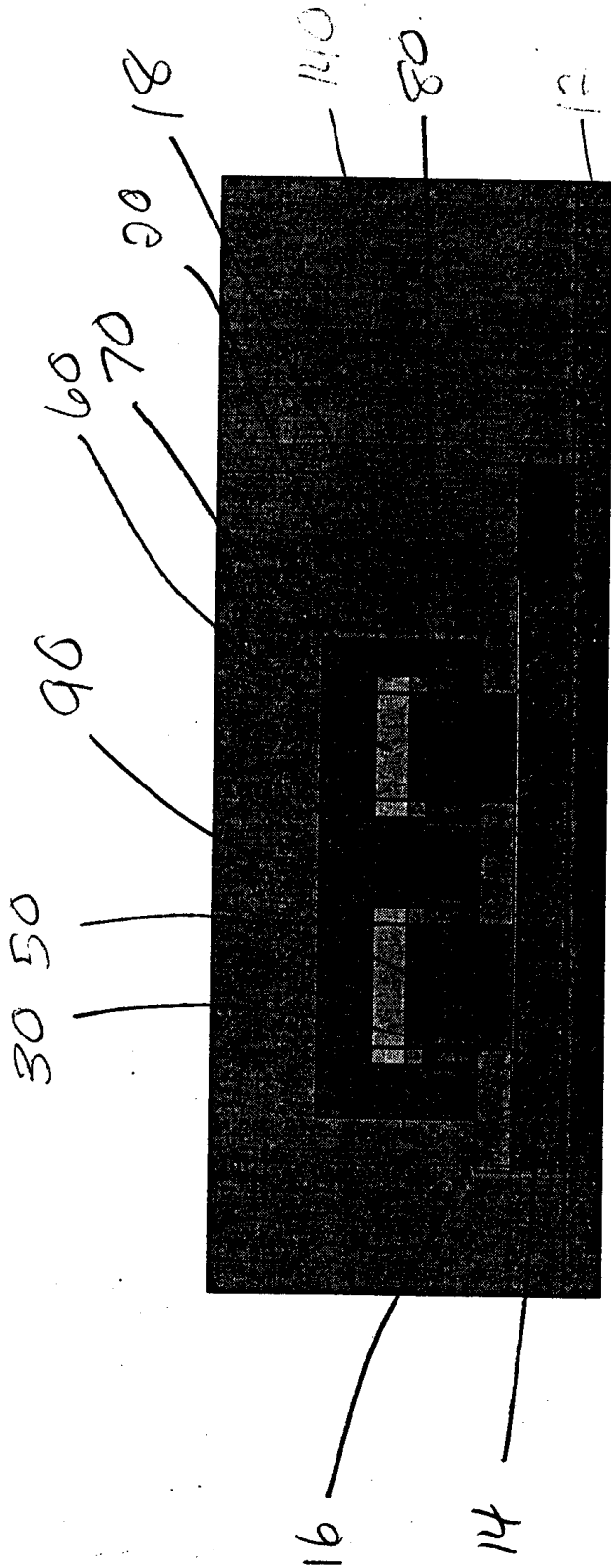


Figure 14

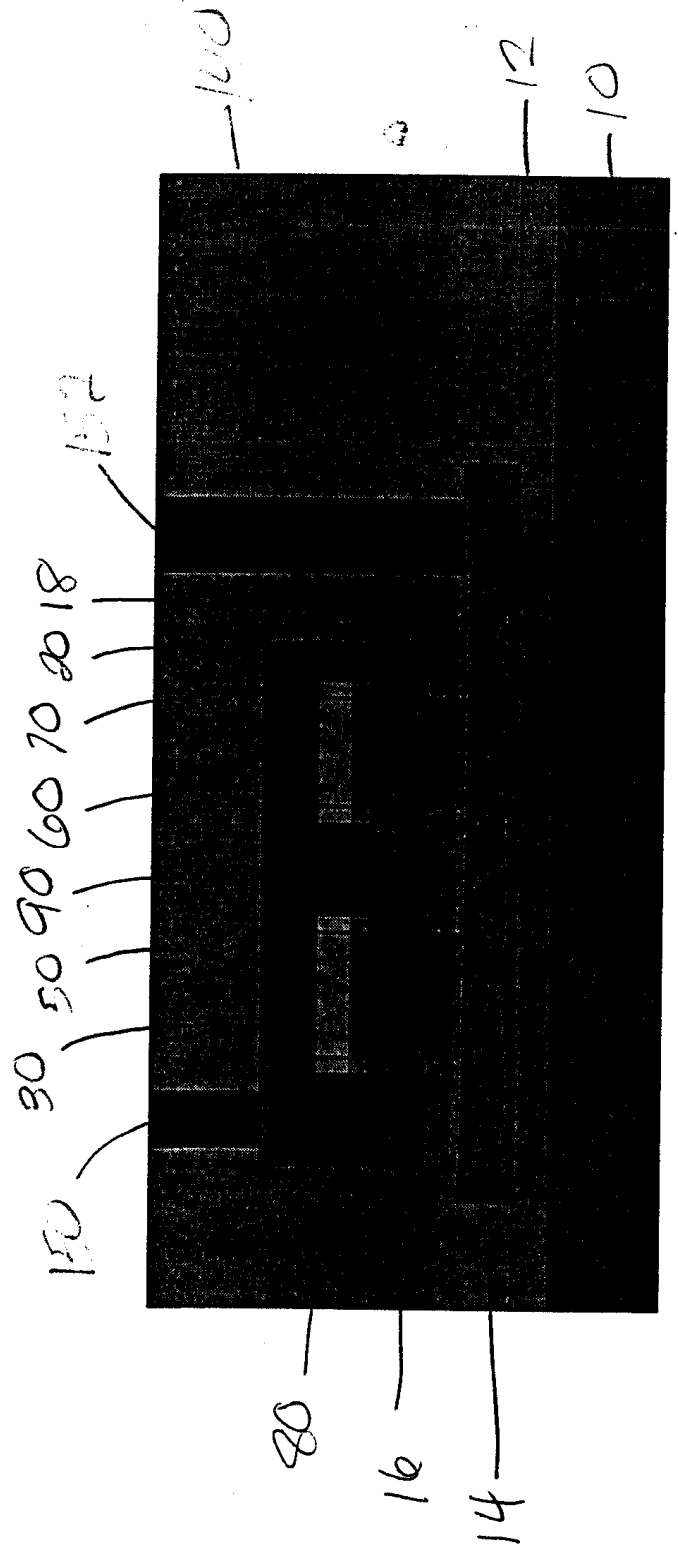
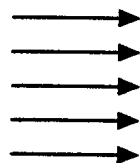


Figure 15

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Well mask

Mandrel mask



20

Si

18

16

Si

160

162

Si

Si

Ion implant wells

Figure 16

Figure 17

N-well or P-well

164

22

20

18

16

164

160

26

Figure 18

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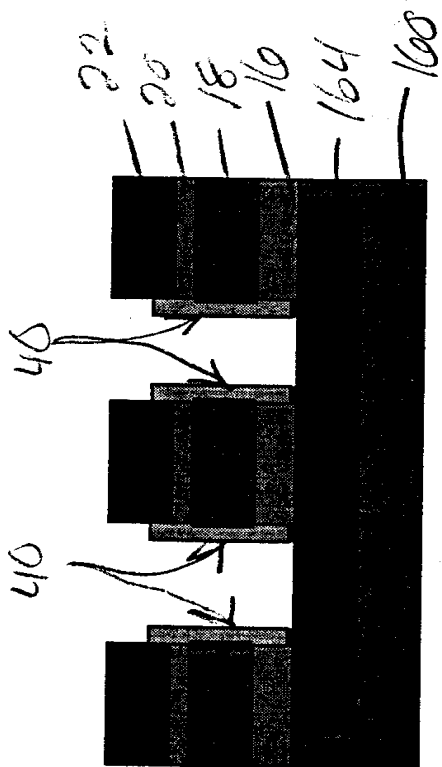


Figure 20

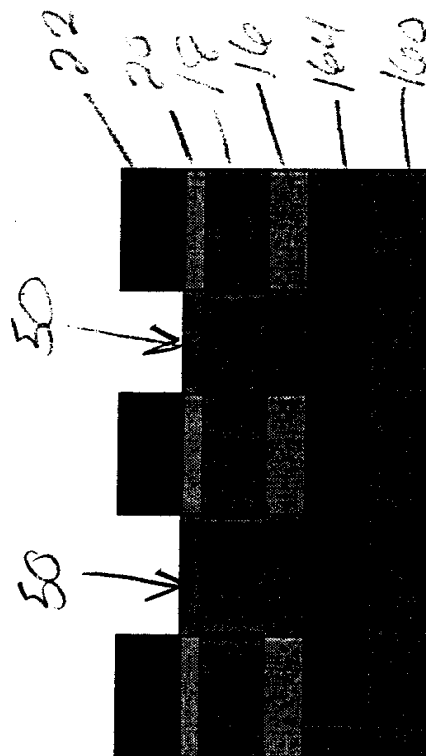


Figure 21

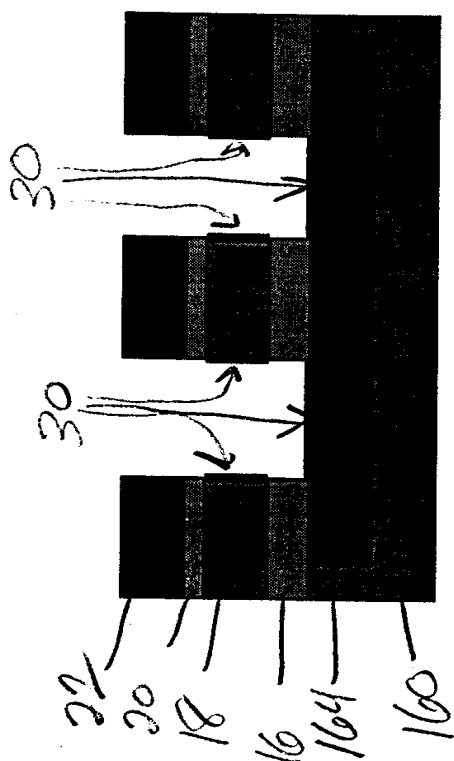


Figure 19



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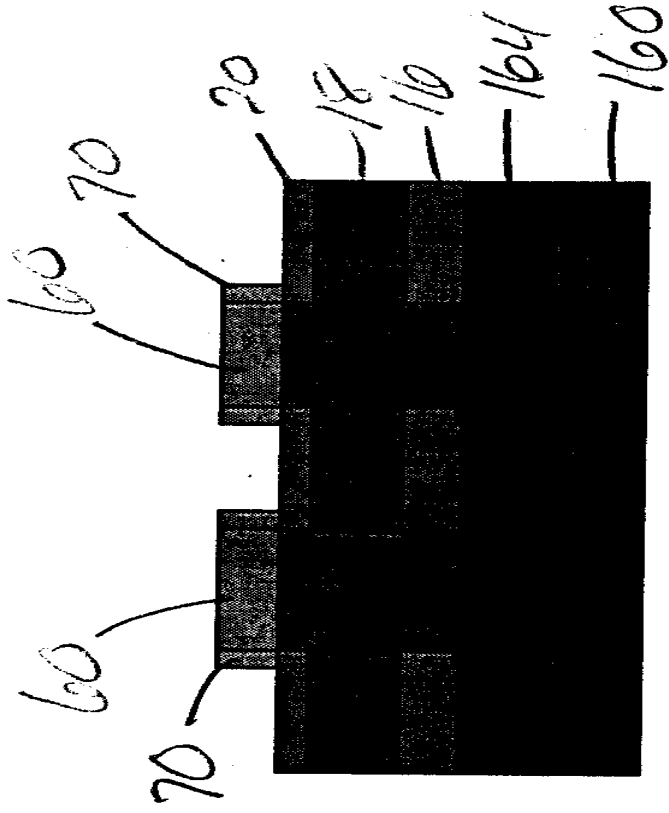


Figure 23

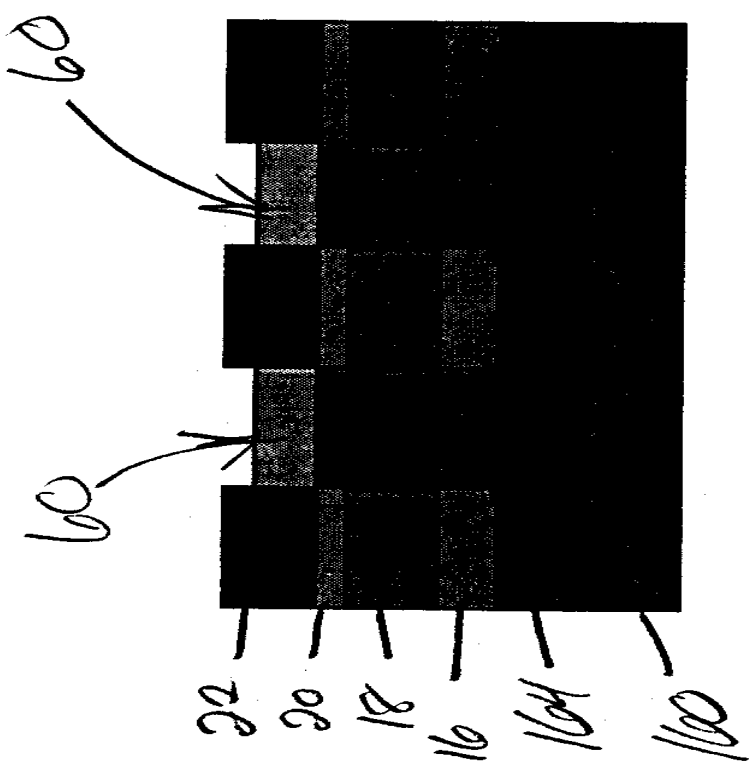


Figure 22

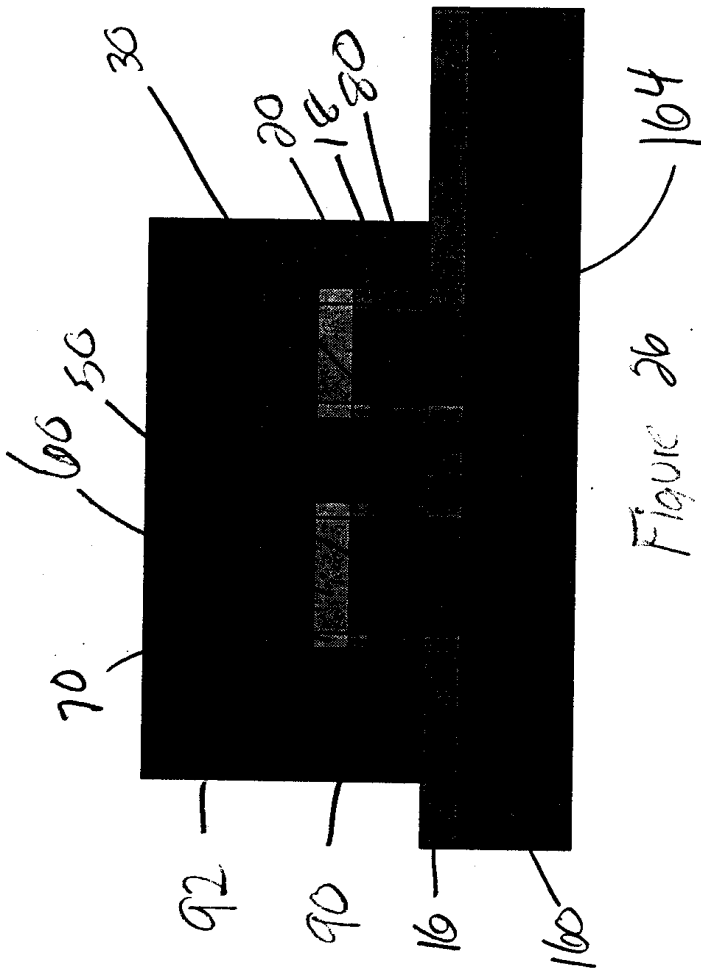


Figure 26

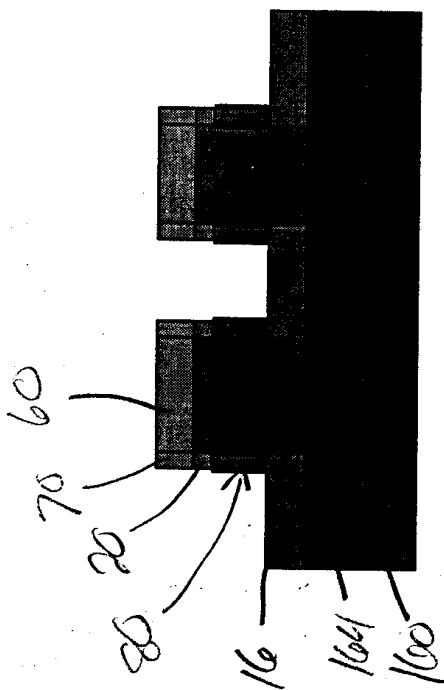


Figure 24

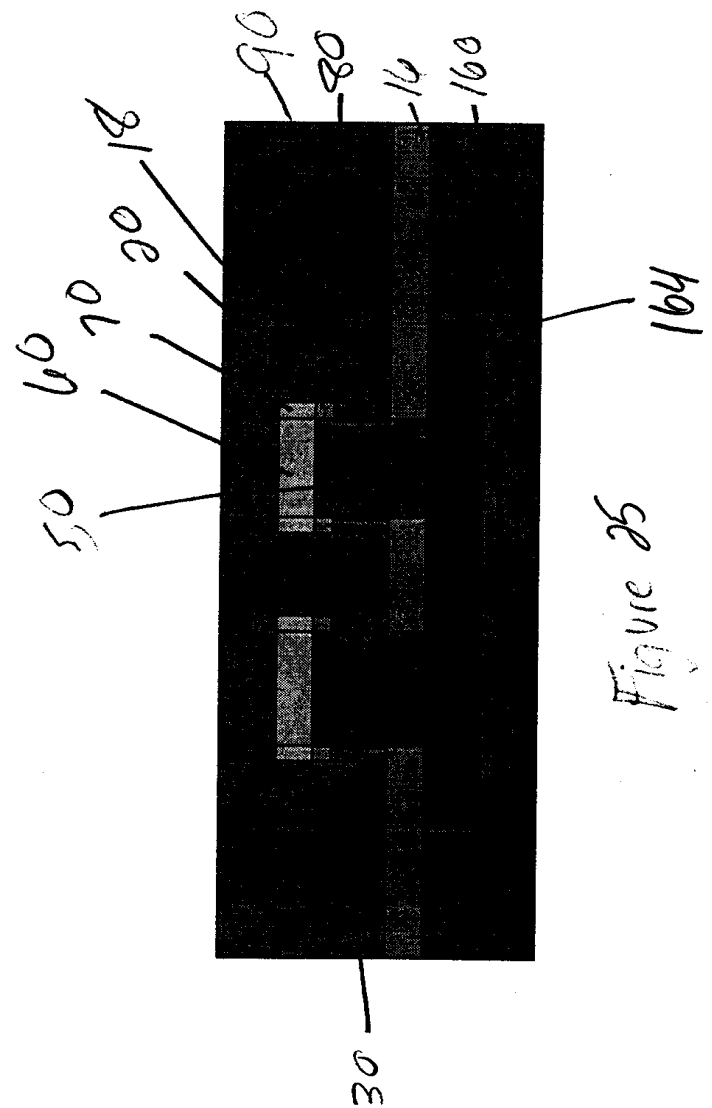
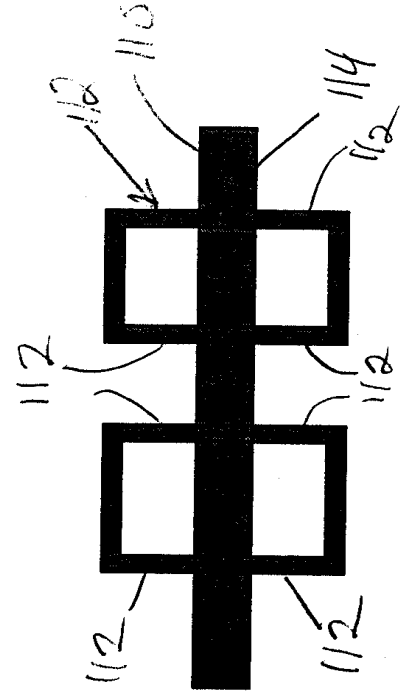


Figure 25



1000

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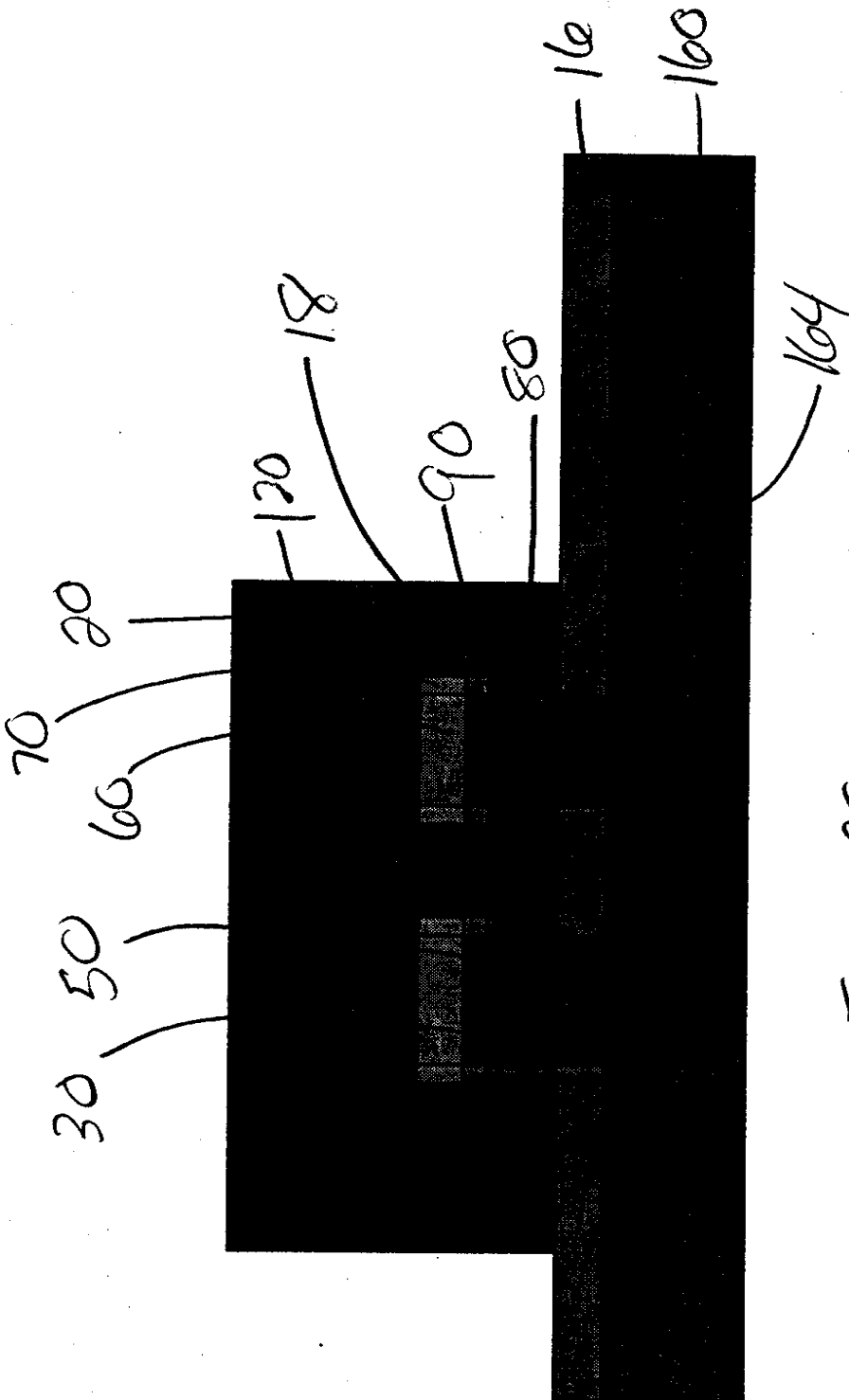
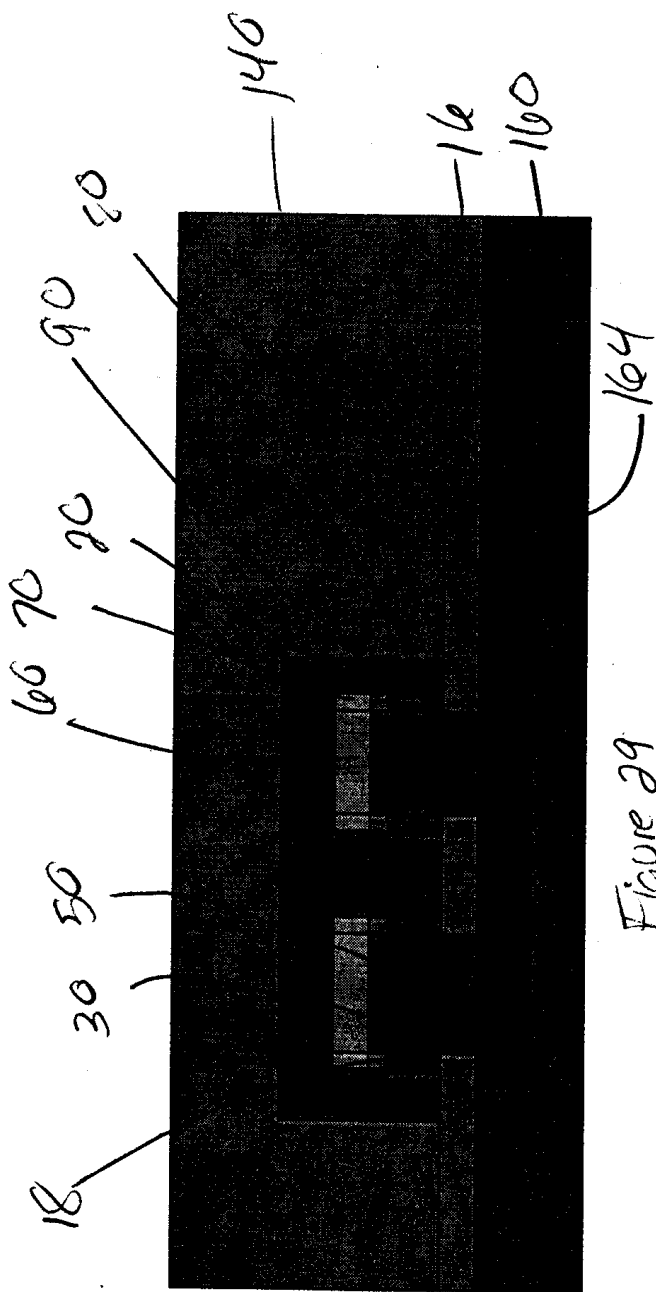
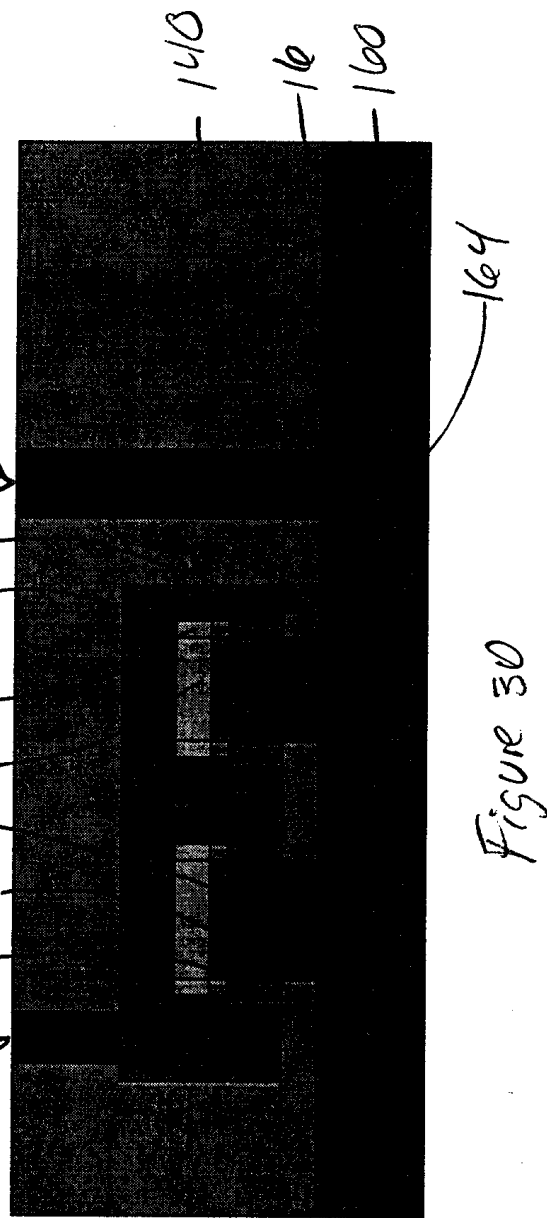


Figure 28

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Via to switching gate 18 30 50 60 70 90 80 152



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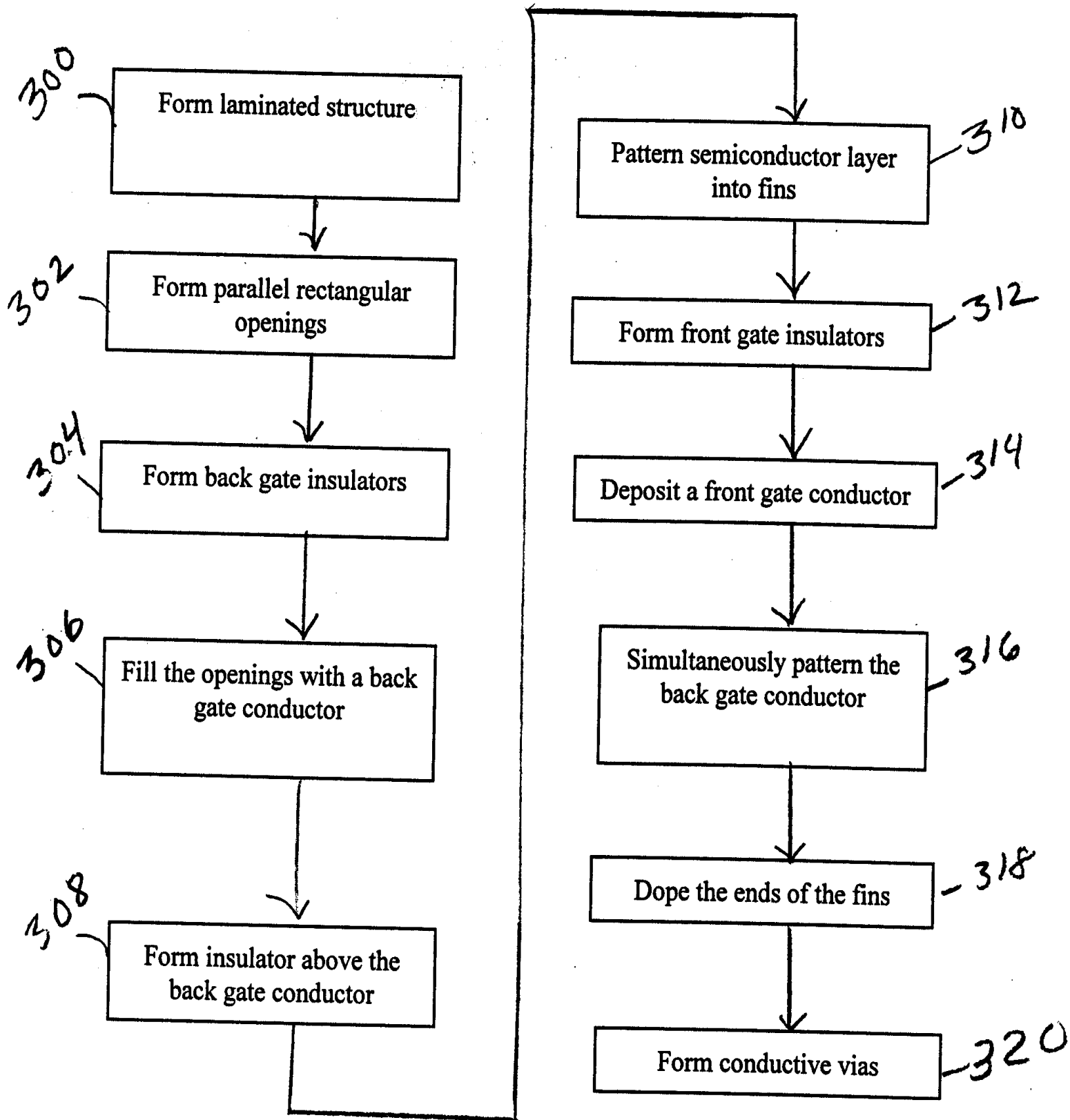


Figure 31